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CONFIRMATION NO. 6728

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|-----------------------------|---------------------------------------|--------------|------------------------|--------------------------------------|
| SERIAL NUMBER 10/634,458 | FILING DATE 08/05/2003 RULE | CLASS 134 | GROUP ART UNIT 1746 | ATTORNEY DOCKET NO. SCF02A-CIP |
|-----------------------------|---------------------------------------|--------------|------------------------|--------------------------------------|

APPLICANTS

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**** CONTINUING DATA *******

This application is a CIP of 09/837,507 04/18/2001 PAT 6,612,317
 which claims benefit of 60/197,519 04/18/2000
 and claims benefit of 60/267,916 02/09/2001
 This application 10/634,458
 is a CIP of 09/861,298 05/18/2001 PAT 6,602,349
 which is a CIP of 09/837,507 04/18/2001 PAT 6,612,317
 which claims benefit of 60/205,335 05/18/2000
JS

**** FOREIGN APPLICATIONS *******

None

IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** SMALL ENTITY **
**** 10/31/2003**

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|---|---------------------------|------------------------|-----------------------|----------------------------|
| Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no | STATE OR COUNTRY MA | SHEETS DRAWING 1 | TOTAL CLAIMS 26 | INDEPENDENT CLAIMS 3 |
|---|---------------------------|------------------------|-----------------------|----------------------------|

35 USC 119 (a-d) conditions met
☐ yes ☒ no ☐ Met after
 Allowance

Verified and Acknowledged
[Signature] Examiner's Signature *JS* Initials

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TITLE
 Supercritical fluid delivery system for semiconductor wafer processing